



TJK/203

**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

In re Patent Application of :	)	APPARATUS AND METHOD
	)	FOR THIN FILM DEPOSITION
Chan-Soo PARK et al.	)	
	)	Examiner: R. Zervigon
Application No. 10/039,357	)	
	)	Art Unit: 1763
Application Filing Date: November 7, 2001	)	
	)	

**RESPONSE TO OFFICE ACTION**

Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450  
Mail Stop: Fee Amendment

Dear Sir:

This paper is in response to the Office Action mailed December 8, 2003.

**IN THE CLAIMS:**

Please amend the claims as follows:

1. (Currently Amended) An apparatus for forming a thin film, comprising:
  - a reaction chamber having a top portion, a sidewall portion and a bottom portion;
  - a gas injector penetrating the top portion and letting a source element pass therethrough;
  - a distributor connected to the gas injector by screw threads, the distributor comprising a first portion having a cylindrical shape, a second portion shaped like a truncated cone, and a plurality of injection holes, wherein a plurality of injection holes are formed in the distributor and the source element is injected through the plurality of injection holes; and